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Analysis of Strained-Si Device including Quantum Effect

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THE POSSIBILITIES ARE INFINITE

Background



The Implementation of Strained Band



Evaluated Structure

• We calculated below Lg=50nm.

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We used Double Gate structure.

Phonon, Impurity and Surface Roughness scattering



 $I_{d} - V_{g} @V_{d} = 0.05V$

- V_d=0.05V
- Drain current is saturated at Ge=20%



 $I_{d} - V_{g} @V_{d} = 0.8V$

• Vd=0.8V

· Drain current is not saturated.



Valley Distribution



The Introduction of Quantum Effect

· We implemented quantum effect by Bohm Potential method



The Comparison with Schrödinger-Poisson



 $I_{d} - V_{d} @V_{g} = 0.8V$



The Comparison of Scattering

Strain Effect

Quantum Effect



Ballistic Rate and I_{on} Improvement



- Ballistic particles exceed 50% at L=10nm.
- $\cdot\,$ Both ballistic rate and $I_{\rm on}$ improvement with quantum effect are larger than with classical.



Summary

•We linked the first principle band calculation program to full-band MC simulator directly.

•We implemented Bohm Potential Quantum correction model and analyzed Strained-Si device including quantum effect.

•As gate length is scaled down, I_{on} improvement by strain effect will decrease, but In the regime that ballistic transport is dominant (about below 10nm), strain effect will increase again due to increasing injection velocity from source region.

